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**AMENDMENT UNDER 37 CFR 1.116
EXPEDITED PROCEDURE -
TECHNOLOGY CENTER 1700**

Box AF
Assistant Commissioner for Patents
Washington, D.C. 20231

PATENT
Attorney Docket No.: 018867-000410US

On October 10 2002

TOWNSEND and TOWNSEND and CREW LLP
By: [Signature]

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:
SHUZO FUJIMURA et al.
Application No.: 09/328,939
Filed: June 9, 1999
For: **SURFACE TREATMENT
METHOD AND EQUIPMENT**

Examiner: Shamim Ahmed
Art Unit: 1746

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**AMENDMENT UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
TECHNOLOGY CENTER 1700**

Box AF
Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:
In response to the Final Office Action mailed July 1, 2002, please amend this application as follows:

IN THE CLAIMS:

Please amend claims 1 and 5, cancel claim 3, and add new claims 23-29 as follows:

1. (Amended) A method of surface treatment in a substantially downstream position of a plasma source to substantially be free from an undesirable influence of a reactive species from the plasma source, where an object to be processed is downstream from the plasma source, the method comprising generating a plasma